



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Peter J. de Groot Art Unit : 2877
Serial No. : 10/659,060 Examiner : Unknown
Filed : September 9, 2003
Title : INTERFEROMETRY METHOD FOR ELLIPSOMETRY, REFLECTOMETRY, AND SCATTEROMETRY MEASUREMENTS, INCLUDING CHARACTERIZATION OF THIN FILM STRUCTURES

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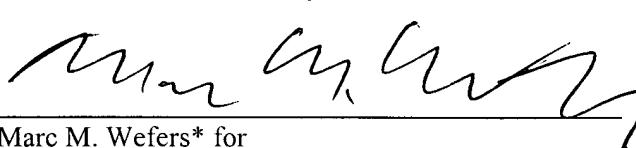
SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Applicant submits the references listed on the attached form PTO-1449.

This statement is being filed within three months of the filing date of the application or before the receipt of a first Office action on the merits. Please apply any charges or credits to Deposit Account No. 06-1050, referencing Attorney Docket No. 09712-332001.

Respectfully submitted,

Date: 3/11/04


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*See attached document certifying that Marc M. Wefers has limited recognition to practice before the U.S. Patent and Trademark Office under 37 C.F.R. § 10.9(b).

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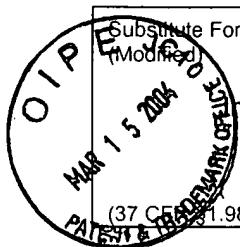
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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 09712-332001	Application No. 10/659,060
Information Disclosure Statement by Applicant (Use several sheets if necessary)		Applicant Peter J. de Groot	
		Filing Date September 9, 2003	Group Art Unit 2877

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	4,999,014	03/12/1991	Gold et al.	356	382	
	AB	5,133,601	07/28/1992	Cohen et al.	356	359	
	AC	5,602,643	02/11/1997	Barrett	356	360	
	AD	6,545,763	04/08/2003	Kim et al.	356	503	
	AE	6,597,460	07/22/2003	Groot et al.	356	512	
	AF						
	AG						

Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AH							
	AI							

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
	AJ	Dresel, Thomas et al., "Three-dimensional sensing of rough surfaces by coherence radar", <u>Applied Optics</u> , Vol. 31, No. 7, pp. 919-925 (March 1, 1992)
	AK	Feke, Gilbert D. et al., "Interferometric back focal plane microellipsometry", <u>Applied Optics</u> , Vol. 37, No. 10, pp. 1796-1802 (April 1, 1998)
	AL	Kim, Seung-Woo et al., "Thickness-profile measurement of transparent thin-film layers by white-light scanning interferometry", <u>Applied Optics</u> , Vol. 38, No. 28, pp. 5968-5973 (October 1, 1999)
	AM	Kino, Gordon S. et al., "Mirau correlation microscope", <u>Applied Optics</u> , Vol. 29, No. 26, pp. 3775-3783 (September 10, 1990)
	AN	Pelligrand, S. et al., "Mesures 3D de topographies et de vibrations a l'echelle (sub)micrometrique par microscopie optique interferometrique", <u>Proc. Club CMOI, Methodes et Techniques Optiques pour l'Industrie</u> (2002)
	AO	Pluta, Maksymilian, "Advanced Light Microscopy", Vol. 3, (Elsevier, Amsterdam, 1993) pp. 265-271
	AP	Rosencwaig, Allan et al., "Beam profile reflectometry: A new technique for dielectric film measurements", <u>Applied Physics Letters</u> , Vol. 60, No. 11, pp. 1301-1303 (March 16, 1992)
	AQ	Sandoz, Patrick "Wavelet transform as a processing tool in white-light interferometry", <u>Optics Letters</u> , Vol. 22, No. 14, pp. 1065-1067 (July 15, 1997)
	AR	Shatalin, S.V. et al., "Reflection conoscopy and micro-ellipsometry of isotropic thin film structures", <u>Journal of Microscopy</u> , Vol. 179, Part 3, pp. 241-252 (September, 1995)

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	